

Microfabrication of large area high-stress silicon nitride membranes for optomechanical devices

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<http://arxiv.org/abs/1601.02669>

Diavolezza cQOM workshop
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DI TRENTO

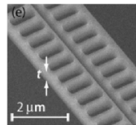
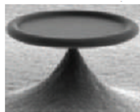
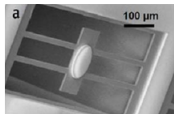


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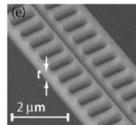
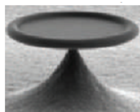
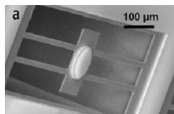
Consiglio Nazionale delle Ricerche

Motivation



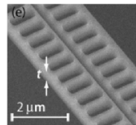
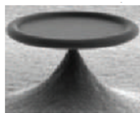
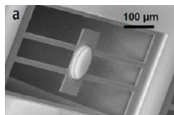
- low losses mechanical resonator for optical cavities
- SiN membranes

Motivation



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Motivation



- low losses mechanical resonator for optical cavities
 - SiN membranes
- freely selectable shape
 - controlled high internal stress

Microfabrication process

1) LPCVD TEOS (200 nm)



2) LPCVD SiN (100 nm)



3) Back-side etching (RIE)



4) Sputtering pure-Al (1 μm)



5) PECVD SiO2 back-side (6 μm)



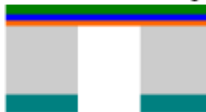
6) Back-side lithography



Microfabrication process

7) Back-side dry etching (SiO_2)

8) DRIE silicon etching



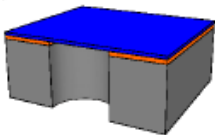
9) Pure-Al wet etching (PES)



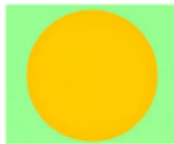
10) TEOS wet etching (HF)



11)



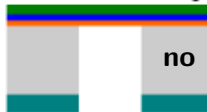
12)



Microfabrication process

7) Back-side dry etching (SiO_2)

8) DRIE silicon etching



no KOH etching!

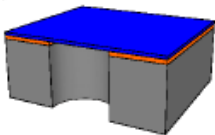
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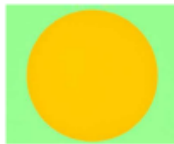
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11)



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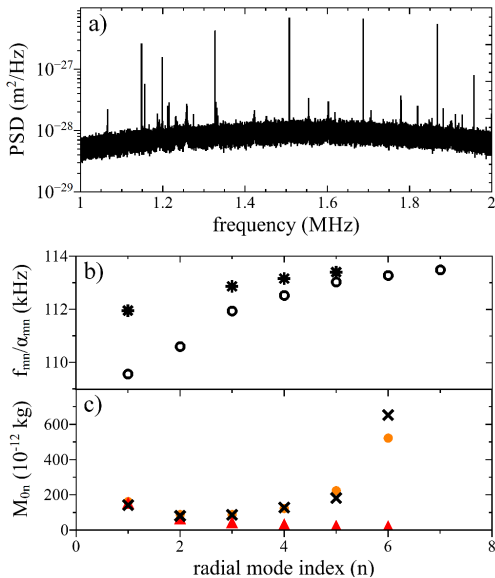


Resonance frequencies of circular membranes

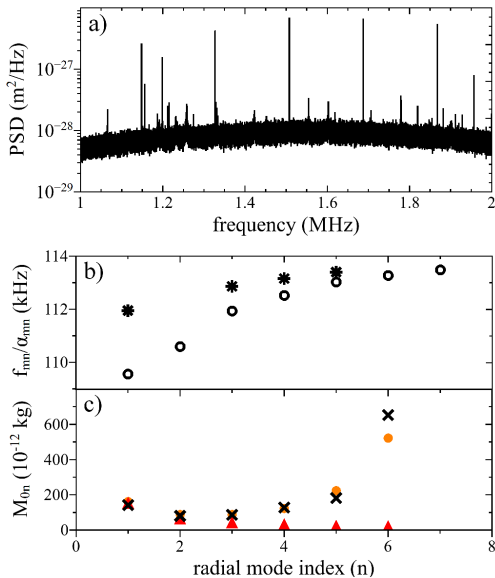
- resonance frequencies

$$f_{mn} = f_0 \alpha_{mn}, \quad f_0 \equiv \frac{1}{2\pi R} \sqrt{\frac{T}{\rho}}, \quad J_m(\alpha_{mn}) = 0$$

Resonance frequencies of circular membranes

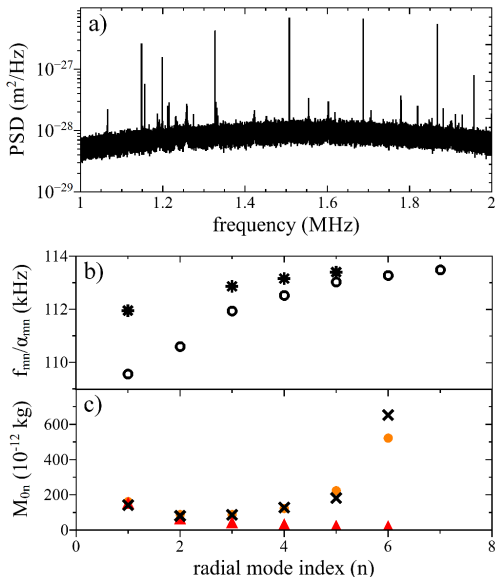


Resonance frequencies of circular membranes



$$f_0 \simeq 114 \text{ kHz}$$

Resonance frequencies of circular membranes



$$f_0 \simeq 114 \text{ kHz}$$

$$R = 0.75 \text{ mm}$$

$$T = 1 \text{ GPa}$$

$$\rho = 3200 \text{ kgm}^{-3}$$

$$f_0 = 118.6 \text{ kHz}$$

Effective mass

- effective mass dependent on modal index
 - pointlike readout:

$$M_{0n} = M J_1^2(\alpha_{0n})$$

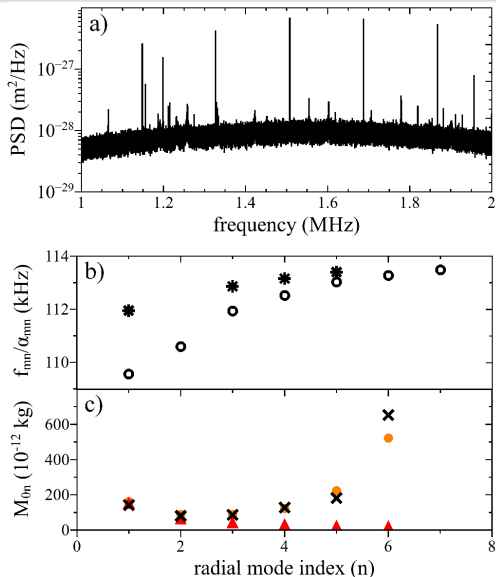
- Gaussian readout:

$$M_{0n} = M \left(\frac{J_1(\alpha_{0n})}{\frac{4}{w^2} \int J_0(\alpha_{0n} r/R) \exp\left(-\frac{2r^2}{w^2}\right) r dr} \right)^2$$

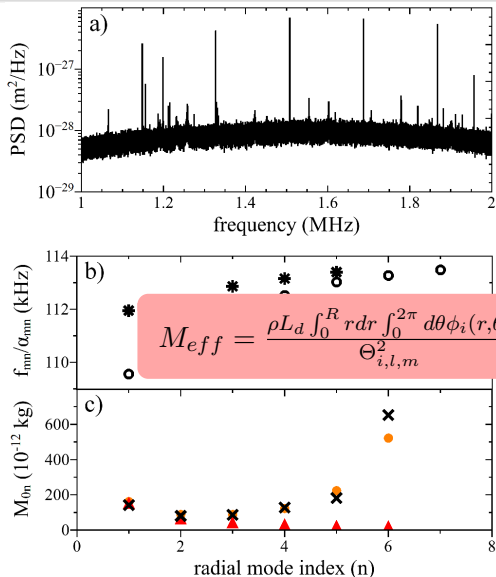
- experimentally obtained from the areas of the thermal peaks

$$A_{0n} = \frac{kT}{M_{0n} (2\pi f_{0n})^2}$$

Effective mass



Effective mass



Q-factor

- at room temperatures ranging from few thousands to 2×10^5
- at cryogenic temperatures globally higher:

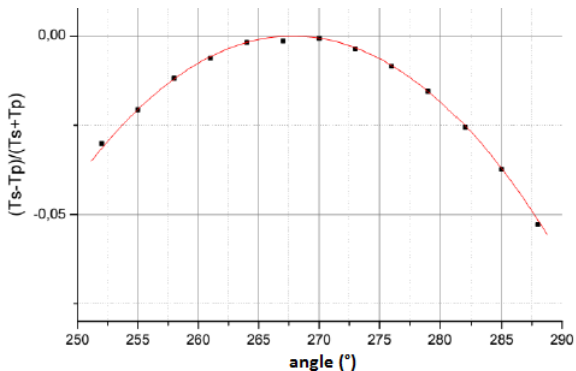
$R = 0.75$ mm, 5 mm side frame

$$Q_{max} = 0.65 \times 10^6 @ 8 \text{ K}$$

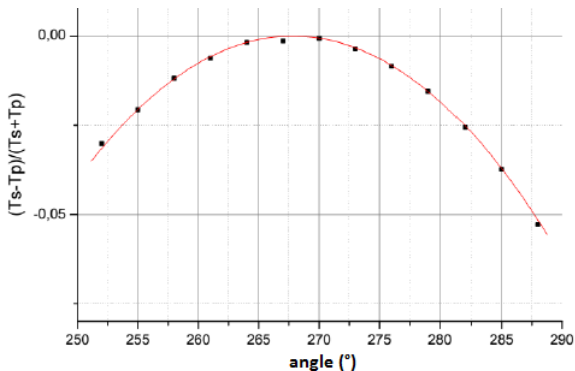
$a = 1$ mm, 5×20 mm² frame

$$Q_{max} = 1.3 \times 10^6 @ 13 \text{ K}$$

Optical properties of circular membranes



Optical properties of circular membranes



$$L_d = 97.27 \pm 0.01 \text{ nm}$$
$$n_R = 2.0210 \pm 0.0005 \text{ @ } \lambda = 1064 \text{ nm}$$

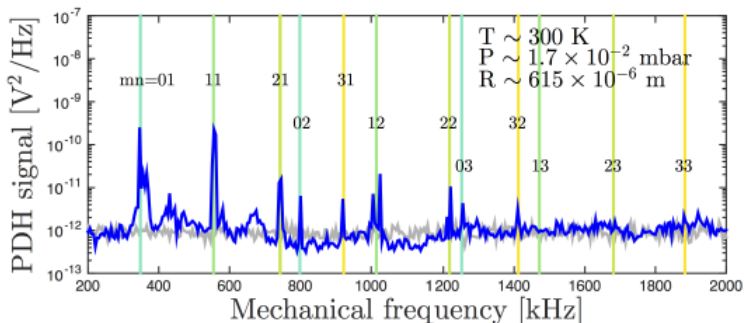
Optical properties of circular membranes

- reflection and transmission coefficients of the membrane,
 $\beta \equiv nkL_d$

$$r_d = \frac{(n^2 - 1) \sin \beta}{2in \cos \beta + (n^2 + 1) \sin \beta}$$
$$t_d = \frac{2n}{2in \cos \beta + (n^2 + 1) \sin \beta}$$

$$\Rightarrow |r_d|^2 = 0.355 \pm 0.002$$

Optical properties of circular membranes



$$f_{01} \sim 348.5 \text{ kHz}$$

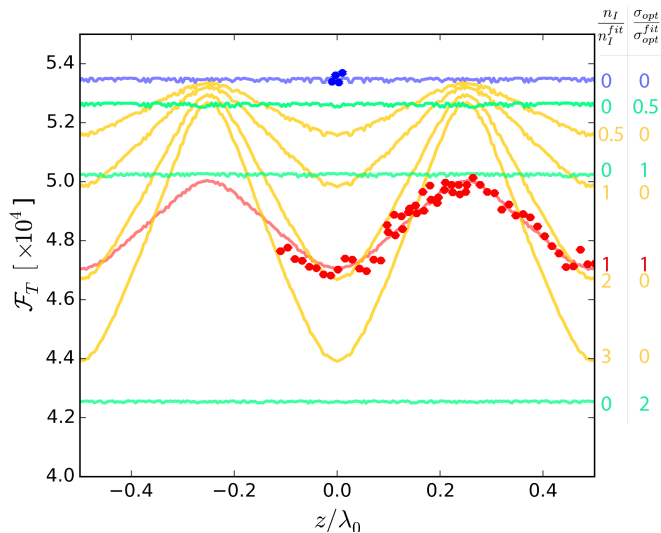
Finesse measurement

- ringdown technique, $\mathcal{F} = \pi c\tau/L$
- intensity transmission of the cavity assuming $r_1 = r_2 = \sqrt{\mathcal{R}}$ and $t_1 = t_2 = \sqrt{\mathcal{T}}$

$$\mathcal{T}_c = \frac{|\mathcal{T}t_d|^2}{\left|1 + 2r_d\sqrt{\mathcal{R}}\cos(2kz)e^{ikL} + \mathcal{R}(t_d^2 + r_d^2)e^{2ikL}\right|^2}$$

- optical roughness $\sigma_{opt} \Rightarrow \sqrt{\exp[-(2k\sigma_{opt})^2]}$
- $L_d = 97$ nm, $n_R = 2.021$, $L = 9.03$ cm, $\lambda = 1064$ nm, $\mathcal{F}_v = 53520$

Finesse measurement



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- $L_d = 97$ nm, $n_R = 2.021$, $L = 9.03$ cm, $\lambda = 1064$ nm,
 $\mathcal{F}_v = 53520$

- $n_I = (1.97 \pm 0.08) \times 10^{-6}$
- $\sigma_{opt} = (287 \pm 4)$ pm

- Norcada 1 mm side, 50 nm thickness membrane:
 $n_I = (1.0 \pm 0.01) \times 10^{-5}$, $\sigma_{opt} = (280 \pm 10)$ pm

Auxiliary slides

- intensity reflection and transmission coefficients

$$R_P = \left(\frac{n \cos \theta_i - \cos \theta_t}{n \cos \theta_i + \cos \theta_t} \right)^2, \quad R_S = \left(\frac{\cos \theta_i - n \cos \theta_t}{\cos \theta_i + n \cos \theta_t} \right)^2$$

$$T_{S,P} = \left(1 + \frac{4R_{S,P}}{(1 - R_{S,P})^2} \sin^2(\beta \cos \theta_t) \right)^{-1}, \quad \beta \equiv nkL_d$$

Auxiliary slides

